



5-12-2015

Statistical Process Control of Alignment Module of NX2600

Hironmichi Yamamoto
Singh Center, hyam@seas.upenn.edu

Follow this and additional works at: https://repository.upenn.edu/scn_tooldata

Yamamoto, Hironmichi, "Statistical Process Control of Alignment Module of NX2600", *Tool Data*. Paper 29.
https://repository.upenn.edu/scn_tooldata/29

This paper is posted at ScholarlyCommons. https://repository.upenn.edu/scn_tooldata/29
For more information, please contact repository@pobox.upenn.edu.

Statistical Process Control of Alignment Module of NX2600

Keywords

Statistical Process Control, NX2600

Creative Commons License

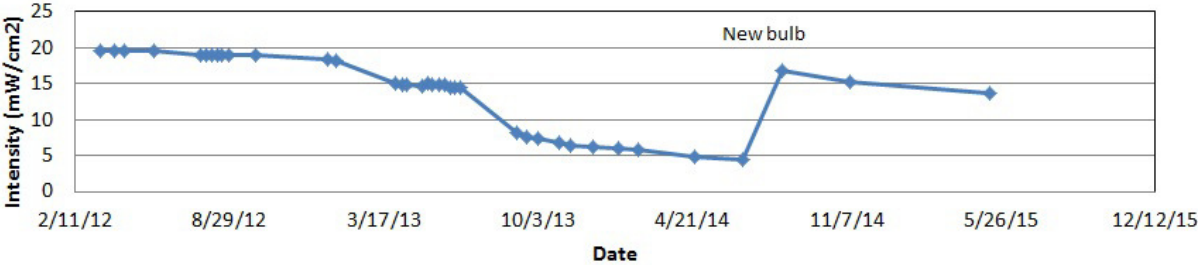


This work is licensed under a [Creative Commons Attribution-Share Alike 4.0 International License](https://creativecommons.org/licenses/by-sa/4.0/).

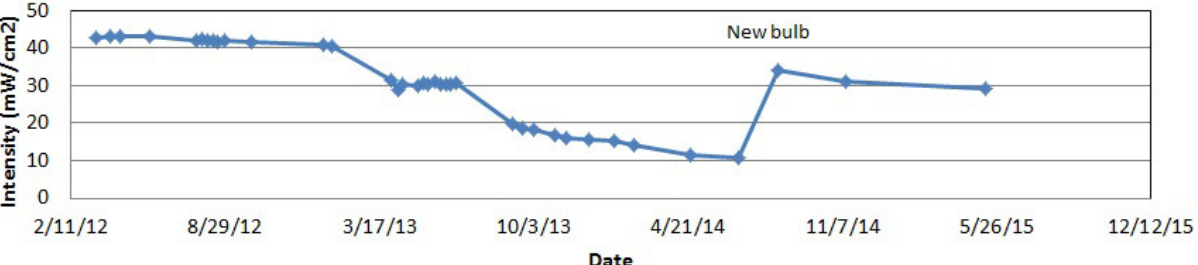
Statistical Process Control of Alignment Module of NX2600 Nanoimprint/Mask Aligner

Hirromichi Yamamoto (5/12/2015)

Statistical Process Control of UV light Intensity at 365 nm of NX2600



Statistical Process Control of UV light Intensity at 405 nm of NX2600



Statistical Process Control of Uniformity of UV light Intensity at 365 and 405 nm

